



9/8.0.T.
OK
9/26/03

PATENT
005586/D8326 (81784.0208)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Hidenori OGATA et al.

Serial No: 09/291,538

Filed: April 14, 1999

Confirmation No. 2245

For: LASER ANNEAL METHOD OF A
SEMICONDUCTOR LAYER

Art Unit: 2822

Examiner: M.A. Wilczewski

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

Mail Stop RCE
Commissioner for Patent
P. O. Box 1450, Alexandria, VA 22313-1450, on

September 10, 2003

Date of Deposit

John P. Scherlacher, Reg. No. 23,009

Name

John P. Scherlacher 09/10/03

Signature

Date

PETITION FOR EXTENSION OF TIME

Mail Stop RCE

Commissioner for Patents

P. O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to September 10, 2003, the period for response to the final Office Action dated March 10, 2003. A check for \$930 is enclosed. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

09/16/2003 DTESSEN1 00000162 09291538

02 FC:1253

930.00 OP

Date: September 10, 2003

Respectfully submitted,

HOGAN & HARTSON L.L.P.

By:

John P. Scherlacher
Registration No. 23,009
Attorney for Applicant(s)

500 South Grand Avenue, Suite 1900
Los Angeles, California 90071
Phone: 213-337-6700
Fax: 213-337-6701

RECEIVED
SEP 23 2003
TECHNOLOGY CENTER 2800